FORM HDP-1449 (Based on Form PTO-1449)

PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Sheet 1 of 2

ATTORNEY DOCKET NO.	SERIAL NO.	
7784-000425DVA Not Yet Assigned		
APPLICANT		
Minas H. Tanielian		
FILING DATE	GROUP 3729	
Herewith Not Yet Assigned		

U.S. P	U.S. PATENT DOCUMENTS						
Ref. Desig.	Exami		Document Number	Date	Name	Class/ Subclass	(If appropriate) Filing Date
1.	TI	<u>U</u>	3,456,134	7/15/1969	Ко		
2.		1	3,466,473	9/9/1969	Rhoten		
3.			3,553,588	1/5/1971	W. Honig		
4.			3,624,451	11/30/1971	Gauld, et al.		
5.			4,467,236	8/21/1984	Kolm et al.		
6.			4,510,484	4/9/1985	Snyder		
7.			5,463,374	10/31/1995	Mendez et al.		
8.			5,751,091	5/12/1998	Takahashi		
9.			5,801,475	9/1/1998	Kimura		·
10.			6,306,773	10/23/2001	Adas et al.		·
11.			6,382,026 B1	5/7/2002	Tajika et al.		
12.			6,407,484	5/12/1998	Takahashi		
13.	1 7	N	6,530,276 B2	3/11/2003	Tajika et al.		

FORE	FOREIGN PATENT DOCUMENTS						
Ref. Desig.	Examiner's Initials	Document Number	Date	Country	Class/ Subclass	Translati Yes	on No
1.	TN	2 026 284	7/17/1979	UK			
2.	TN	2 064 883	11/25/1980	UK		<u> </u>	

				, ,		
Examiner:	Vac tiguyen	Date Considered:	6	128/0	ry	
	www off					

FORM HDP-1449 (Based on Form PTO-1449)

PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Sheet 2 of 2

ATTORNEY DOCKET NO.	SERIAL NO.		
7784-000425DVA Not Yet Assign			
APPLICANT			
Minas H. Tanielian			
FILING DATE	GROUP : 3729		
Herewith Not Yet Assigne			

OTHE	OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)					
Ref. Desig.	Examiner's Initials					
1.	TN	F. J. von Preissig and E.S. Kim, Topics in Finite-Element Modeling of Piezoelectric MEMS.				
2.		Ibong Jung and Yongrae Roh, Design and fabrication of piezoceramic biomorph vibration sensors, Sensors and Actuators A 69 (1998) pp. 259-266.				
3.		John Kymissis, Clyde Kendall, Joseph Paradiso, Neil Gershenfeld, "Parasitic Power Harvesting in Shoes", 8/1998, p. 1-8.				
4.		Kloeppel, James E., Residual stress in piezoelectric ceramics can be reduced, put to work, News Bureau, (Sept. 1, 2000).				
5.	IN	Meteer, Jami, Front-Side Processing of a Piezoelectric MEMS Accelerometer, The Pennsylvania State University National Nanofabrication Users Network, pp. 48-49.				

Examiner:	Ver tranger	Date Considered:	6/28/04	
Examinot.	un i			

DEC 1 7 2003 63

RM HDP-1449 (Based on Form PTO-1449)

PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Sheet 1 of 1

ATTORNEY DOCKET NO.	SERIAL NO.	
7784-000425DVA 10/717,354		
APPLICANT		
Minas H. Tanielian		
FILING DATE	GROUP : 3729	
November 19, 2003	Not Yet Assigned	

U.S. P	ATENT DO	CUMENTS				<u> </u>
Ref. Desig.	Examiner's Initials	Document Number	Date	Name	Class/ Subclass	(If appropriate) Filing Date
1.	TN	5,632,841	5/27/1997	Hellbaum et al.		
2.	Ī	5,849,125	12/15/1998	Clark	-	
3.	The	6,162,313	12/19/2000	Bansemir et al.		

OTHE	R DOCUME	NTS (including Author, Title, Date, Pertinent Pages, etc.)
Ref. Desig.	Examiner's Initials	
1.	IN	2001 Face International Corporation, "Thunder White Paper", February 21, 2001, Pgs 1-10

Examiner: Law Layuyeu Date Considered: 6/28/04